

ABSTRACT

METHOD FOR IMPLANTING IONS ON A SURFACE OF AN OBJECT TO
BE TREATED AND INSTALLATION FOR IMPLEMENTING THIS METHOD

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The invention relates to a method for the implantation of mono- or multi-charged ions on a surface of an object to be treated (24) placed in a vacuum chamber (20), this method comprising the step that consist simultaneously of:

10 - injecting into the vacuum chamber (20) a beam of ions (30) produced by a source of ions (26) and directing this beam of ions (30) towards the surface of the object to be treated (24), and

 - illuminating the surface of the object to be treated (24) by means of a source of ultraviolet radiation (32) producing ultraviolet radiation (36) that propagates in the vacuum chamber (20).

15 The invention also relates to an ion implantation installation (18) for implementing the implantation method.

Figure 3